



Group Art Unit:

Attorney Docket No: 98-058/1D

For: **Confinement Device for Use in Dry Etching of Substrate Surface and Method of Dry Etching a Wafer Surface**

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Box DAC, Assistant Commissioner for Patents, Washington, D.C. 20231.

Maria Kovacs
Maria Kovacs

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JUL 31 2001
OFFICE OF PETITIONS

Dear Sir:

The Applicants respectfully petition the Commissioner to change the order of the names on a joint application pursuant to 37 C.F.R. 1.182, and further request that the petition fee set forth in § 1.17 (h) be charged against the Deposit Account No. 12-2252 of LSI Logic Corporation.

In particular, the Applicants request that the following inventor be the first listed inventor associated with the subject application: Kunal N. Taravade.

It is believed that all of the requirements for requesting a change in the order of names as set forth in M.P.E.P. § 605.04 (f) have been satisfied. If it is felt for any reason that direct communication with the Applicant's attorney would serve to advance prosecution of this case to finality, the Examiner is invited to call the undersigned Peter P. Scott at the telephone number below.

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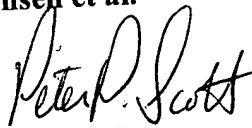
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**AUTHORIZATION TO PAY AND PETITION
FOR THE ACCEPTANCE OF ANY NECESSARY FEES**

If any charges or fees must be paid in connection with this communication (including but not limited to the payment of an extension fee or issue fees), or if any overpayment is to be refunded in connection with the present application, any such charges or fee, or any such overpayment may be respectively paid out of, or into, the Deposit Account No. 12-2252 of LSI Logic Corporation. If any such payment also requires a Petition or Extension Request, please construe this authorization as the required Petition or Request.

Respectfully submitted,

Jurgensen et al.



By: Peter P. Scott
Attorney for Applicant
Reg. No. 33,279

LSI Logic Corporation
1551 McCarthy Blvd
M/S AD-106
Milpitas, CA 95035

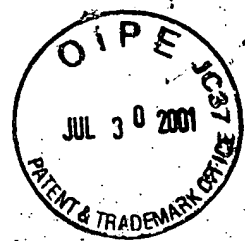
719.533.7969 (Voice)
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PTO Box DAC

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kunal Taravade et. al.

Serial No.:

Filed:

For:

June 18, 2001

Confinement Device for Use in Dry Etching of
Substrate Surface and Method of Dry Etching
a Wafer Surface

Group Art Unit 1763

Examiner Alva Powell

Atty Docket: SYM/LSI-105A / 9

RP-058/1D

HONORABLE COMMISSIONER:

Please acknowledge receipt of the following documents:

— Status request dated: _____ Power of attorney Dated _____

— Change of Correspondence Address PTO/SB/122 Dated: _____

— Certification of Assignee under 37 CFR 3.73(b)

Please date stamp received and deposit in U.S. Mail.

Evidence of assignment.

Date Mailed Via First Class Mail: July 25, 01

Z Petition to change the
order of names on a
Joint Application.

COPY